

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q90606

Akira KOBAYASHI, et al.

Appln. No.: 10/550,897

Group Art Unit: 2812

Confirmation No.: 1704

Examiner: Kevin M. PICARDAT

Filed: September 27, 2005

For: CHEMICAL VAPOR DEPOSITED FILM BASED ON A PLASMA CVD METHOD
AND MEHTOD OF FORMING THE FILM

AMENDMENT UNDER 37 C.F.R. § 1.111

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

A petition and the required fee for a two month extension of time are being submitted herewith to extend the time period from April 14, 2008 to June 16, 2008 (June 14, 2008 being a Saturday).

In response to the Office Action dated January 14, 2008, please amend the above-identified application as follows on the accompanying pages.

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